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HIPRES[®] HP1000

High Pressure Transducer

- Silicon-on-Sapphire sensor technology for outstanding performance
- Pressure ranges to 5,000 bar (72,500 psi)
- Pressure diaphragm and process connection is machined from one piece of Titanium with no seals or welds
- High resistance to overpressure and pressure transients
- ATEX/IECEx option available (includes M1 for mining applications) for 4-20 mA versions
- DNV-GL certification available



The advanced sensor design consists of a piezoresistive silicon strain gauge circuit, which is epitaxially grown onto the surface of a sapphire diaphragm to form a single crystalline structure. The sapphire sensor element is then molecularly bonded to a titanium alloy sub-diaphragm.

This enables the sensor to endure higher over-pressures and provides superb corrosion resistance. The sensor exhibits virtually no hysteresis and excellent long-term stability over wide temperature ranges.

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